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COMPUTER PROGRAMS FOR ELLIPSOMETRY II

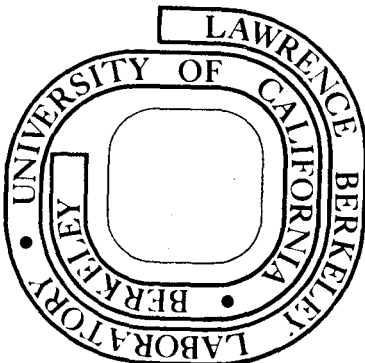
H. J. Mathieu

December 1973

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COMPUTER PROGRAMS FOR ELLIPSOMETRY II

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ABSTRACT

This report describes two additional computer programs in Fortran IV language for use in interpreting ellipsometer measurements. One program considers the case of a substrate covered with two films of different refractive index and of different thickness, the other a substrate covered with an inhomogeneous film with continuously varying refractive index, represented by multiple films of equal thickness and monotonically varying optical properties.

I. FORTRAN IV COMPUTER PROGRAM "DUALF"

This program will evaluate ellipsometer-quantities ψ and Δ of a substrate covered with two homogeneous parallel films of variable thickness¹ (Fig. 1a). It makes partial use of a previous program "LAYER", which assumes coverage by only one film, and "CMOC", which converts reflection coefficient into the complex refractive index of a bare surface.²

Program "DUALF" computes ψ and Δ in two steps. In the first step one assumes that the substrate (see Fig. 1b) is only covered with one film (Film 2) of thickness T_2 . Film 1 is assumed as the incident medium. Drude's equation^{1,3} is applied to determine the complex ratio of reflection coefficients, ρ , defined as

$$\rho = \frac{r_p}{r_s}$$

with r_p as the reflection coefficient for the component parallel to the plane of incident and r_s for the component perpendicular to the plane of incidence.

Once ρ is computed, one can determine the effective complex refractive index n'_s of the combined system of substrate and Film 2 of thickness T_2 . This new refractive index n'_s is used in the second step as the new substrate covered with Film 1 of thickness T_1 (Fig. 1c). These new data of substrate S' and Film 1 are applied to Drude's equation again to determine ρ' , which can be converted to ψ and Δ , according to

$$\rho' = \tan\psi \exp(i\Delta)$$

Computations are performed by systematically combining all prescribed values of optical constants and film thicknesses for both layers with fixed properties of substrate and incident media.

This program was tested for decreasing film thickness of Film 2 (TI→0Å) and $n_2 \rightarrow n_1$ to give the same results as program "LAYER".

A. Variables Used in the Program DUALF

<u>Name</u>	<u>Description</u>
AC	Analyzer azimuth (zone A3), for dual-film system
DELC	Ellipsometric parameter Δ , for dual-film system
DT	Increment of thickness of Film 2
DTN	Increment of real part of refractive index of Film 2
DTNK	Increment of imaginary part of refractive index of Film 2
DTNKL	Increment of imaginary part of refractive index of Film 1
DTN1	Increment of real part of refractive index of Film 1
DIT	Increment of thickness of Film 1
PC	Polarizer azimuth (zone A3) for dual-film system
PHI1, PHI	Angle of incidence
PSIC	Ellipsometric parameter ψ for dual-film system
TI	Initial thickness of Film 2
TM	Final thickness of Film 2
TN1	Real part of refractive index of Film 2, initial value
TNK1	Imaginary part of refractive index of Film 2
TNKM	Imaginary part of refractive index of Film 2, final value
TNKS	Imaginary part of refractive index of substrate
TNK1I	Imaginary part of refractive index of Film 1, initial value
TNK1M	Imaginary part of refractive index of Film 1, final value
TNM	Real part of refractive index of Film 2, final value
TNO, N	Refractive index of incident medium (real)

TNS Real part of refractive index of substrate
TN1I Real part of refractive index of Film 1, initial value
TN1M Real part of refractive index of Film 1, final value
T1I Initial thickness of Film 1
T1M Final thickness of Film 1
WL Wavelength of light in vacuum

B. Input Format for Program DUALF

Card	1-9	10-19	20-29	30-39	40-49	50-59
1	}	Title and comments (up to 80 columns each)				
2						
3	TNO	WL	TNS	TNKS	PHI	
4	TNI	DTN	TNM	TNKI	DTNK	TNKM
5	TI	DT	TM			
6	TN1I	DTN1	TN1M	TNK1I	DTNK1	TNK1M
7	T1I	D1T	D1M			

These seven cards constitute a set. Any number of sets may follow. Three blank cards must follow the last set of data. The program, together with a sample of output, is reproduced below.

For zone A3, the range of data for polarizer and analyzer readings are³

range of polarizer transmission reading	0-45°
range of analyzer transmission reading	90-180°
compensator circle reading	135°

Azimuth readings differ from circle readings of the present ellipsometer by 90°:

$$P(\text{azimuth}) = P(\text{circle reading}) + 90^\circ$$

$$A(\text{azimuth}) = A(\text{circle reading}) - 90^\circ$$

DUALF

```

PROGRAM DUALF (INPUT,OUTPUT)
C THIS PROGRAM CALCULATES THE ELLIPSO-METRIC PARAMETERS
C DELC,PSIC OF A SUBSTRATE COVERED WITH TWO FILMS.
C THE INCIDENT MEDIUM HAS THE REAL REFRACTIVE INDEX TNO
C FILM (1) HAS THE OPTICAL CONSTANTS TN1 AND TNK1 WITH
C THICKNESS T11 TO T1M
C FILM (2) NEXT TO THE SUBSTRATE HAS THE OPTICAL
C CONSTANTS TN,TNK WITH THICKNESS T1 TO TM
C THE COMPUTATION STARTS FROM THE BOTTOM (SUBSTRATE)
C AC AND PC ARE VALID FORE ZONE A3
COMPLEX TN1,T2,S2,TN3,LN3, LN2 ,S1,T1,SC,CC,D
COMPLEX TN2, CPHI2, CPHI3, R1S, R1P, R2S, R2P, RS, RP, RHO
REAL PHI1,PHI,CP,SP,LNK,LN,L,TN,TNK,T,PSIC,DELC,DT,TM
REAL DTNK1,TNKM,T1M,TN1M,TNK1M,WL,AC,PC
REAL TNKS,TNM,TNO,TNS
REAL TNK1I,TN1I,T1I,TNI,TNKI,TI,DTNK,DTN,D1T,DTN1
DIMENSION TITLE (8), RANGE (8)
1 READ 2, TITLE,RANGE
2 FORMAT (8A10/8A10)
12 3 PRINT 4, TITLE,RANGE
4 FORMAT (1H1, 8A10//8A10)
22 16 READ 17,TNO,WL,TNS,TNKS,PHI1
40 IF (TNO) 3000, 3000, 6
42 6 READ 9, TN1,DTN,TNM,TNK1,DTNK,TNKM
62 7 READ 11, T1,DT,TM
74 5 READ 9,TN1I,DTN1,TN1M,TNK1I,DTNK1,TNK1M
114 8 READ 11,T1I,D1T,T1M
9 FORMAT (F9.0,5F10.0)
11 FORMAT (F9.0, 2F10.0)
17 FORMAT (F9.0,4F10.0)
13 FORMAT (1H0,/6H PHI = ,F5.2,10X,4HN = ,F7.4, 10X, 13HWAVELENGTH =
C F5.0, 11H ANGSTROMS//33H REFRACTIVE INDEX OF SUBSTRATE = , F7.4,
C 2X, 4H- I, F7.4)
14 FORMAT (1H0, 27HREFRACTIVE INDEX OF FILM2= , F7.4, 2X,
C 4H- I, F7.4//18H FILM2 THICKNESS= , F7.2, 10H ANGSTROMS,
C //8H PSIC = , F10.5, 10X, 7HDELC = , F10.5,
C //8H AC = ,F10.5,10X, 7HPC = ,F10.5)
25 FORMAT (1H0, 28HREFRACTIVE INDEX OF FILM1 = ,F7.4, 2X,
C 4H- I, F7.4//19H FILM1 THICKNESS = , F7.2, 10H ANGSTROMS)
126 PHI = 0.01745329252*PHI1
130 CP = COS(PHI)
132 SP = SIN(PHI)
135 TN3 = CMPLX(TNS,-TNKS)
140 LNK=TNK1I
141 23 LN=TN1I
143 22 L=T1I
145 21 TN=TN1
147 20 TNK=TNK1
151 30 T = T1
153 100 TN2 = CMPLX(TN,-TNK)
156 TN1 = CMPLX(LN, -LNK)
161 SC = (TNO*SP)/TN1
172 CC = CSQRT(1. - SC*SC)
203 CPHI3 = CSQRT(1.0 - TN1**2*SC**2/(TN3**2))
236 CPHI2 = CSQRT(1.0 - TN1**2*SC**2/(TN2**2))
271 R1S = (TN1*CC - TN2*CPHI2)/(TN1*CC + TN2*CPHI2)

```


DUALF

```
330 R1P = -(TN1*CPHI2 - TN2*CC)/(TN1*CPHI2 + TN2*CC)
366 R2S = (TN2*CPHI2 - TN3*CPHI3)/(TN2*CPHI2 + TN3*CPHI3)
425 R2P = -(TN2*CPHI3 - TN3*CPHI2)/(TN2*CPHI3 + TN3*CPHI2)
463 D = (0.0,1.0)*(4.0*3.1415927*T/WL)*TN2*CPHI2
501 RS = (R1S + R2S*CEXP(-D))/(1.0 + R1S*R2S*CEXP(-D))
540 RP = (R1P + R2P*CEXP(-D))/(1.0 + R1P*R2P*CEXP(-D))
600 RHO = RP/RS
607 S1 = SC
612 T1 = SC/CC
621 T2 = (1. + RHO)/((1. - RHO)*T1)
647 S2 = T2/CSQRT(1. + T2*T2)
670 LN3 = (TN1*S1)/S2
705 CPHI3 = CSQRT(1.0 - TNO**2*SP**2/(LN3**2))
730 LN2 = CMPLX(LN, -LNK)
733 CPHI2 = CSQRT(1.0 - TNO**2*SP**2/(LN2**2))
756 R1S = (TNO*CP - LN2*CPHI2)/(TNO*CP + LN2*CPHI2)
1010 R1P = -(TNO*CPHI2 - LN2*CP)/(TNO*CPHI2 + LN2*CP)
1041 R2S = (LN2*CPHI2 - LN3*CPHI3)/(LN2*CPHI2 + LN3*CPHI3)
1100 R2P = -(LN2*CPHI3 - LN3*CPHI2)/(LN2*CPHI3 + LN3*CPHI2)
1136 D = (0.0,1.0)*(4.0*3.1415927*L/WL)*LN2*CPHI2
1154 RS = (R1S + R2S*CEXP(-D))/(1.0 + R1S*R2S*CEXP(-D))
1213 RP = (R1P + R2P*CEXP(-D))/(1.0 + R1P*R2P*CEXP(-D))
1252 RHO = RP/RS
1262 PSIC = ATAN(CABS(RHO))/0.01745329252
1266 DELC = ATAN2(AIMAG(RHO), REAL(RHO))/0.01745329252
1276 AC = PSIC + 90.
1277 PC = (90. - DELC)/2.
1301 IF (DELC) 140,140,300
1303 140 DELC = DELC + 360.00
1305 300 PRINT 13, PHI1,TNC,WL,TNS,TNKS
1323 PRINT 25, LN, LNK, L
1335 PRINT 14, TN, TNK, T, PSIC, DELC, AC, PC
1357 400 IF (TM - T) 600,600,500
1362 500 T = T + DT
1364 GO TO 100
1365 600 IF (TNKM - TNK) 800,800,700
1370 700 TNK = TNK + DTNK
1372 GO TO 30
1373 800 IF (TNM - TN) 910, 910,900
1376 900 TN = TN + DTN
1400 GO TO 20
1401 910 IF (T1M - L) 930,930,920
1404 920 L=L+D1T
1406 GO TO 21
1407 930 IF (TN1M - LN) 950,950,940
1412 940 LN=LN+DTN1
1414 GO TO 22
1415 950 IF (TNK1M - LNK) 970,970,960
1420 960 LNK=LNK+DTNK1
1422 GO TO 23
1423 970 GO TO 1
1424 3000 CONTINUE
1425 END
```

EXAMPLE OF OUTPUT

PHI = 75.00 N = 1.3500 WAVELENGTH = 5461 ANGSTROMS
REFRACTIVE INDEX OF SUBSTRATE = .9300 - I 2.3900
REFRACTIVE INDEX OF FILM1 = 1.4500 - I-0.0000
FILM1 THICKNESS = -0.00 ANGSTROMS
REFRACTIVE INDEX OF FILM2= 2.7500 - I .2500
FILM2 THICKNESS= -0.00 ANGSTROMS
PSIC = 37.62461 DELC = 58.93017
AC = 127.62461 PC = 15.53492

PHI = 75.00 N = 1.3500 WAVELENGTH = 5461 ANGSTROMS
REFRACTIVE INDEX OF SUBSTRATE = .9300 - I 2.3900
REFRACTIVE INDEX OF FILM1 = 1.4500 - I-0.0000
FILM1 THICKNESS = -0.00 ANGSTROMS
REFRACTIVE INDEX OF FILM2= 2.7500 - I .2500
FILM2 THICKNESS= 50.00 ANGSTROMS
PSIC = 38.47673 DELC = 52.17989
AC = 128.47673 PC = 18.91005

PHI = 75.00 N = 1.3500 WAVELENGTH = 5461 ANGSTROMS
REFRACTIVE INDEX OF SUBSTRATE = .9300 - I 2.3900
REFRACTIVE INDEX OF FILM1 = 1.4500 - I-0.0000
FILM1 THICKNESS = -0.00 ANGSTROMS
REFRACTIVE INDEX OF FILM2= 2.7500 - I .2500
FILM2 THICKNESS= 100.00 ANGSTROMS
PSIC = 39.72852 DELC = 47.08963
AC = 129.72852 PC = 21.45519

II. FORTRAM IV COMPUTER PROGRAM "MULTF"

This program computes the ellipsometer data ψ and Δ for a system of a substrate covered with m films of monotonically varying refractive index, but of equal thickness.¹ It is based on the same principle as program "DUALF" (see Chapter I). As in program "DUALF" one starts out with the substrate S covered with Film " m " and assumes Film " $m-1$ " as the incident medium (Fig. 2). The program computes the reflexion coefficient ρ_m of this first sub system (Substrate/Film " m "/Film " $m-1$ "). This reflection coefficient ρ_m is converted into an effective refractive index n_{sm} , which serves as the substrate in the second step. In this second step Film " $m-1$ " will serve as the covering film, while Film " $m-2$ " is assumed to be the incident medium. The thickness of each film is assumed to be the same. This procedure is repeated m times until the prescribed number of Films m is reached.

A. Variables Used in the Program MULTF

<u>Name</u>	<u>Description</u>
AC	Analyzer azimuth (zone A3)
DELC	Ellipsometric parameter Δ
DI	Decrement of imaginary part of refractive index of film-layers (between two successive layers)
DR	Decrement of real part of refractive index of film-layers
K	Number of film-layers of thickness T (referred to as m)
PC	Polarizer azimuth (zone A3)
PHI1	Angle of incidence ϕ
PSIC	Ellipsometric parameter ψ
T	Thickness of individual film-layer

<u>Name</u>	<u>Description</u>
TNI	Real part of refractive index of first layer
TNKI	Imaginary part of refractive index of first layer
TNKS	Imaginary part of refractive index of substrate
TNO	Refractive index of incident medium (real)
TNS	Real part of refractive index of substrate
WL	Wavelength

B. Input Format for Program MULTF

<u>Card</u>	1-9	10-19	20-29	30-39	40-49	50-59
1	}	Title and comments (up to 80 columns)				
2						
3	TNO	WL	TNS	TNKS	PHI1	
4	TNI	TNKI	DR	DI	T	K (column 50-52)

These four cards constitute a set. Any number of sets may follow.

Three blank cards must follow the last set of data. Note, that the number of films K is an integer variable of three digits (column 50-52).

The program, together with a sample of output, is reproduced below.

```
PROGRAM MULTF (INPUT,OUTPUT)
C THIS PROGRAM CALCULATES THE ELLIPSOMETRIC PARAMETERS
C DELC,PSIC OF A SUBSTRATE COVERED WITH MULTIPLE FILMS
C OF EQUAL THICKNESS, BUT OF A STEPWISE CHANGE
C OF THE COMPLEX REFRACTIVE INDEX
C THE INCIDENT MEDIUM HAS THE REAL REFRACTIVE INDEX TNO
C THE COMPUTATION STARTS FROM THE BOTTOM (SUBSTRATE)
C AC AND PC ARE VALID FORE ZONE A3
COMPLEX T2,S2,TN3,D
COMPLEX TN2, CPHI2, CPHI3, R1S, R1P, R2S, R2P, RS, RP, RHO
REAL PHI1,PHI,CP,SP,LNK,LN,L,TN,TNK,T,PSIC,DELC,DT,TM
REAL DTNK1,TNKM,T1M,TN1M,TNK1M,WL,AC,PC
REAL TNKS,TNM,TNO,TNS
REAL TNK1I,TN1I,T1I,TN1,TNKI,TI,DTNK,DTN,DIT,DTN1
DIMENSION TITLE (8), RANGE (8)
1 READ 2, TITLE,RANGE
2 FORMAT (8A10/8A10)
3 PRINT 4, TITLE,RANGE
4 FORMAT (141, 8A10//8A10)
16 READ 17,TNO ,WL,TNS,TNKS,PHI1
IF (TNO) 3000, 3000, 6
6 READ 9, TN1,TNKI,DR,DI,T ,K
9 FORMAT (F9.0,4F10.0,I3)
17 FORMAT (F9.0,4F10.0)
13 FORMAT (1H0,/6HPHI = ,F5.2,10X,4HN = ,F7.4, 10X, 13HWAVELENGTH = ,
C F5.0, 11H ANGSTROMS//33H REFRACTIVE INDEX OF SUBSTRATE = , F7.4,
C 2X, 4H- I, F7.4)
14 FORMAT (1H0, 31HREFRACTIVE INDEX OF TOP FILM = , F7.4, 2X,
C 4H- I, F7.4//18H FILM THICKNESS= , F7.2, 10H ANGSTROMS,
C //23HNUMBER OF FILM-LAYER = I3,
C //8H PSIC = , F10.5, 10X, 7HDELC = , F10.5,
C //8H AC = ,F10.5,10X, 7HPC = ,F10.5)
J = K + 1
PHI = 0.01745329252*PHI1
CP = COS(PHI)
SP = SIN(PHI)
TN3 = CMPLX(TNS,-TNKS)
21 TN=TN1
20 TNK=TNKI
TN1 = TNO
N = 0
U = 0.
R = 0.
501 CONTINUE
502 TN2 = CMPLX(TN,-TNK)
SC = SP
CC = CP
CPHI3 = CSQRT(1.0 - TN1**2*SC**2/(TN3**2))
CPHI2 = CSQRT(1.0 - TN1**2*SC**2/(TN2**2))
R1S = (TN1*CC - TN2*CPHI2)/(TN1*CC + TN2*CPHI2)
R1P = -(TN1*CPHI2 - TN2*CC)/(TN1*CPHI2 + TN2*CC)
R2S = (TN2*CPHI2 - TN3*CPHI3)/(TN2*CPHI2 + TN3*CPHI3)
R2P = -(TN2*CPHI3 - TN3*CPHI2)/(TN2*CPHI3 + TN3*CPHI2)
D = (0.0,1.0)*(4.0*3.1415927*R/WL)*TN2*CPHI2
RS = (R1S + R2S*CEXP(-D))/(1.0 + R1S*R2S*CEXP(-D))
```

```
RP = (R1P + R2P*CEXP(-D))/(1.0 + R1P*R2P*CEXP(-D))
RHO = RP/RS
PSIC = ATAN(CABS(RHO))/0.01745329252
DELC = ATAN2(AIMAG(RHO), REAL(RHO))/0.01745329252
AC = PSIC + 90.
  PC = (90. - DELC)/2.
  IF (DELC) 140,140,300
140 DELC = DELC + 360.00
300 PRINT 13, PHI1,TNO,WL,TNS,TKNS
  R = U*T
  PRINT 14, TN ,TNK,R,N,PSIC,DELC,AC,PC
  S1 = SC
  T1 = SC/CC
  T2=(1. + RHO)/((1. - RHO)*T1)
  S2=T2/CSQRT(1. + T2*T2)
  TN3=(TN1*S1)/S2
  TN = TN - DR
  TNK = TNK - DI
  N = N + 1
  U = U + 1.
  IF (N - J) 501,3000,3000
3000 CONTINUE
END
```

EXAMPLE OF OUTPUT

TEXT *** 3 ***

MULTIFILM

PHI = 75.00 N = 1.3500 WAVELENGTH = 5461 ANGSTROMS

REFRACTIVE INDEX OF SUBSTRATE = .9800 - I 2.3900

REFRACTIVE INDEX OF TOP FILM = 2.7650 - I .2500

FILM THICKNESS = 0.00 ANGSTROMS

NUMBER OF FILM-LAYER = 0

PSIC = 37.62461 DELC = 58.93017

AC = 127.62461 PC = 15.58492

PHI = 75.00 N = 1.3500 WAVELENGTH = 5461 ANGSTROMS

REFRACTIVE INDEX OF SUBSTRATE = .9800 - I 2.3900

REFRACTIVE INDEX OF TOP FILM = 2.7500 - I .2500

FILM THICKNESS = 100.00 ANGSTROMS

NUMBER OF FILM-LAYER = 1

PSIC = 37.62461 DELC = 58.93017

AC = 127.62461 PC = 15.53492

PHI = 75.00 N = 1.3500 WAVELENGTH = 5461 ANGSTROMS

REFRACTIVE INDEX OF SUBSTRATE = .9800 - I 2.3900

REFRACTIVE INDEX OF TOP FILM = 2.7350 - I .2500

FILM THICKNESS = 200.00 ANGSTROMS

NUMBER OF FILM-LAYER = 2

PSIC = 39.72939 DELC = 46.01971

AC = 129.72939 PC = 21.99015

ACKNOWLEDGEMENTS

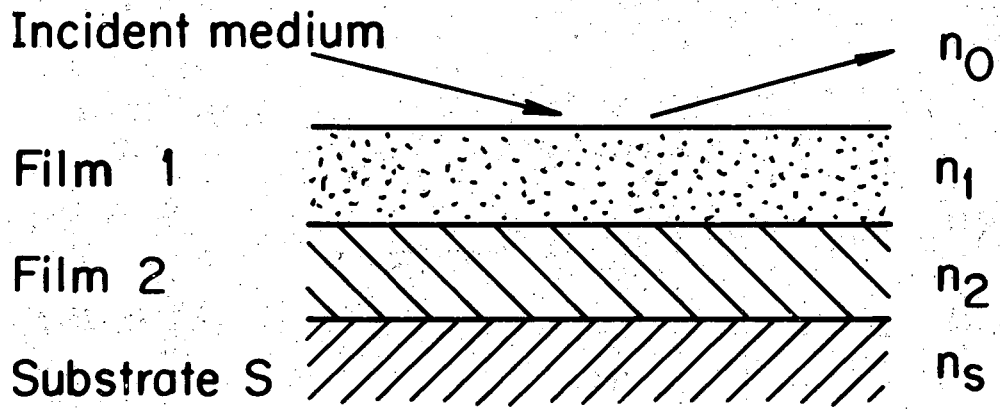
This work was conducted under the auspices of the U. S. Atomic Energy Commission. I wish to thank the Deutsche Forschungsgemeinschaft for its financial support.

REFERENCES

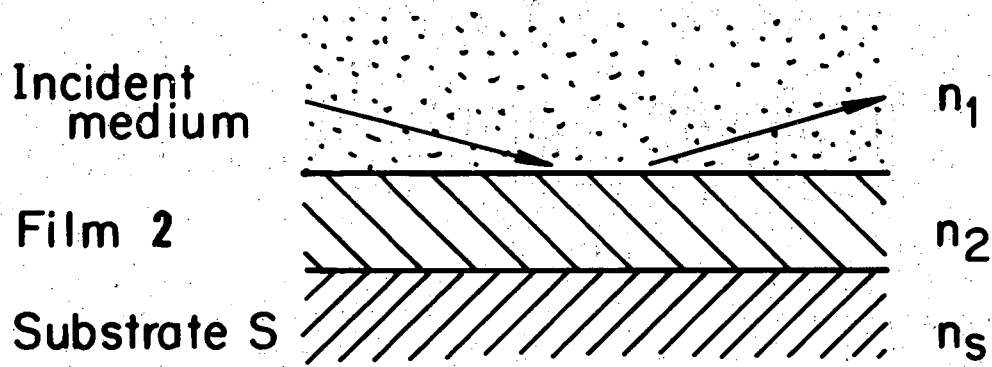
1. O. S. Haevens, Optical Properties of Thin Solid Films (Doves Publishing, Inc., N. Y., 1965).
2. H. J. Mathieu, Computer Programs for Ellipsometry, LBL-1470, University of California, Berkeley, 1973.
3. R. H. Muller in Advances in Electrochemistry and Electrochemical Engineering, Vol. 9, R. H. Muller, ed. (Wiley-Interscience, N. Y., 1973), p. 167f.

FIGURE CAPTIONS

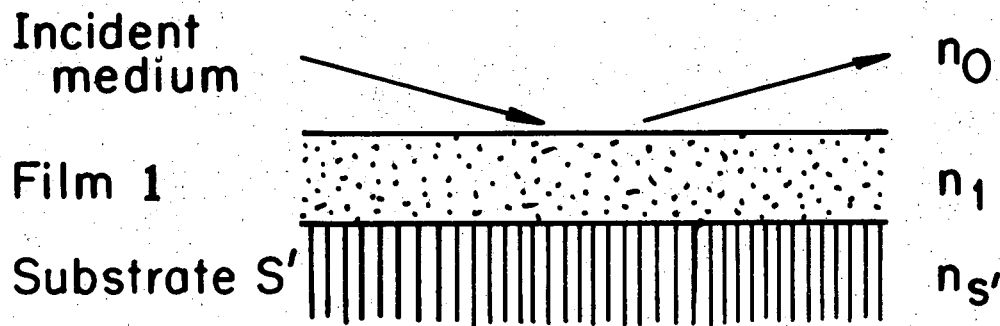
- Fig. 1. (a) Model for a two-film coverage of the substrate.
(b) Step 1. Film 1 is assumed to be the incident medium.
(c) Step 2, using the new refractive index n'_s (Step 1) as effective refractive index of an apparent substrate S' , Film 1 is assumed to cover the substrate S' .
- Fig. 2. Inhomogeneous film represented by m layers of equal thickness with increments in optical constants Δn and Δk between successive layers.



(a)



(b)



(c)

XBL7312-6966

Fig. 1

Incident medium

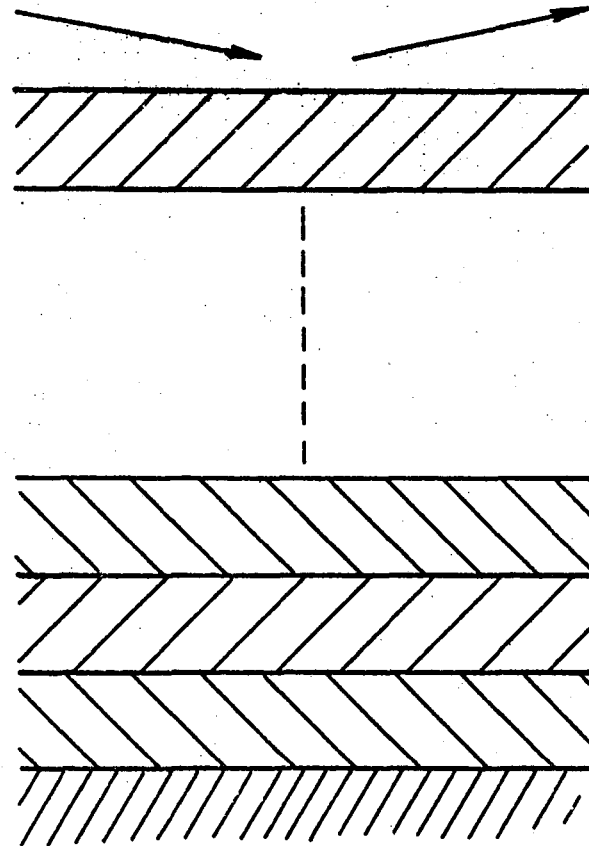
Film 1

Film $m-2$

Film $m-1$

Film m

Substrate



$$n_0$$

$$\hat{n}_1 = n - m \Delta n - i(k - m \Delta k)$$

$$\hat{n}_{m-2} = n - 2\Delta n - i(k - 2\Delta k)$$

$$\hat{n}_{m-1} = n - \Delta n - i(k - \Delta k)$$

$$\hat{n}_m = n - ik$$

$$n_s$$

Fig. 2

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